

Attorney Docket No. 5308-127DV

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Allen *et al.*

Serial No.: To Be Assigned

Filed: Concurrently Herewith

For: METHODS OF FABRICATING SILICON CARBIDE METAL-  
SEMICONDUCTOR FIELD EFFECT TRANSISTORS

Date: November 12, 2003

Mail Stop PATENT APPLICATION  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Sir:

Please enter the following Preliminary Amendment before examining the present application.

**Amendments to the Title** begin on page 2 of this paper.

**Amendments to the Specification** begin on page 3 of this paper.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 4 of this paper.

**Remarks** begin on page 16 of this paper.

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**In the Title:**

Please delete the title in all occurrences and substitute the following title therefor: -- METHODS OF FABRICATING SILICON CARBIDE METAL-SEMICONDUCTOR FIELD EFFECT TRANSISTORS--.